WHAT IS CLAIMED IS:

1. A substrate container system, comprising:

a container body having a bottom face, a front opening that enables passage of a substrate, and a back opening opposing the front opening,

the back opening having a width smaller than that of the front opening; and

a back cover that covers the back opening and establishes sealing engagement with the container body,

wherein the back cover comprises a first gas inlet structure that bendingly extends under the bottom face of the container body upon assembly;

wherein the first gas inlet structure comprises a downward facing gas intake port opposing the bottom face of the container body.

2. The substrate container system of claim 1, wherein the back cover further comprises a second gas inlet structure, wherein the first and the second gas inlet structures are substantially symmetrically arranged along a width direction of the back cover.

3. The substrate container system of claim 2, wherein the container body is configured to receive a filter member that covers the back opening of the container body.

4. The substrate container system of claim 3, wherein each of the first and the second gas inlet structures is connected to a gas guiding channel that extends along a height direction of the back cover.

5. The substrate container system of claim 4, wherein the gas guiding channel has an outlet arranged substantially in a middle section along the height direction of the back cover.

6. The substrate container system of claim 5,
wherein the back cover and the filter member cooperatively define a buffering compartment connected to the gas guiding channel via the outlet.

7. The substrate container system of claim 5,

wherein the back cover comprises a pair of partition structures respectively adjacent the back opening in the width direction, extending along the height direction,

wherein the outlet of the gas guiding channel is formed in the pair of partition structures.

8. The substrate container system of claim 7,
wherein the container body further comprises a pair of flange portions arranged opposing the front opening and respectively adjacent the back opening along the width direction;

wherein the back cover at least partially overlaps the pair of flange portions, wherein the gas guiding channel is formed in an overlapped region between the back cover and the pair of flange portions of the container body.

9. The substrate container system of claim 3, further comprising the filter member having a gas dispensing surface that extends toward the container body through the back opening.

10. The substrate container system of claim 3, further comprising a sealing member having a first seal ring portion arranged between the back cover and the container body, wherein the first seal ring portion comprises a section that bendingly extends between the bottom face of the container body and both the first and the second gas inlet structures.

11. The substrate container system of claim 10, wherein the sealing member further comprises a second seal ring portion arranged between the filter member and the container body.

12. A substrate container system, comprising:

a container body having a bottom face, a front opening that enables passage of a substrate, and a back opening opposing the front opening,

wherein the container body is configured to receive a filter member that covers the back opening of the container body;

a back cover that establishes sealing engagement with the container body;

wherein the back cover and the filter member cooperatively defines a buffering compartment; and

a first gas guiding channel that extends along a height direction of the back cover;

wherein the first gas guiding channel has an outlet connected to the buffering compartment.

13. The substrate container system of claim 12, wherein the outlet is arranged substantially in a middle section along the height direction of the back cover.

14. The substrate container system of claim 12,

wherein the back cover comprises a pair of partition structures respectively adjacent the back opening in a width direction, extending along the height direction,

wherein the outlet of the first gas guiding channel is formed in the pair of partition structures.

15. The substrate container system of claim 12,

wherein the container body further comprises a pair of flange portions arranged opposing the front opening and respectively adjacent the back opening along a width direction;

wherein the back cover at least partially overlaps the pair of flange portions,

wherein the first gas guiding channel is formed in an overlapped region between the back cover and the pair of flange portions of the container body.

16. The substrate container system of claim 12, further comprising a second gas guiding channel, wherein the first and the second gas guiding channels are substantially symmetrically arranged along a width direction of the back cover.

17. The substrate container system of claim 12,
wherein the back cover further comprises a first gas inlet structure that bendingly extends under the bottom face of the container body upon assembly; and

wherein the first gas inlet structure connects the first gas guiding channel and comprises a downward facing gas intake port opposing the bottom face of the container body.

18.The substrate container system of claim 12, further comprising the filter member having a gas dispensing surface, wherein a surface area of the gas dispensing surface is greater than that of the back opening.

19. The substrate container system of claim 17, further comprising a sealing member having a first seal ring portion arranged between the back cover and the container body, wherein the first seal ring portion comprises a section that bendingly extends between the bottom face of the container body and both the first and the second gas inlet structures.

20. The substrate container system of claim 19, wherein the sealing member further comprises a second seal ring portion arranged between the filter member and the container body.